INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)

Docket Number (Optional) TW1-8520	Application Number NEW 10/717, 316
Applicant(s) Allan Rosencwaig et al.	*
Filing Date HEREWITH	Group Art Unit Unknown 2877

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Examiner	Date Considered 23 July 2004
Examiner: Initial if citation considered, whether or not citation i not in conformance and not considered. Include copy of this form	s in conformance with MPEP Section 609; Draw line through citation if n with next communication to applicant.